

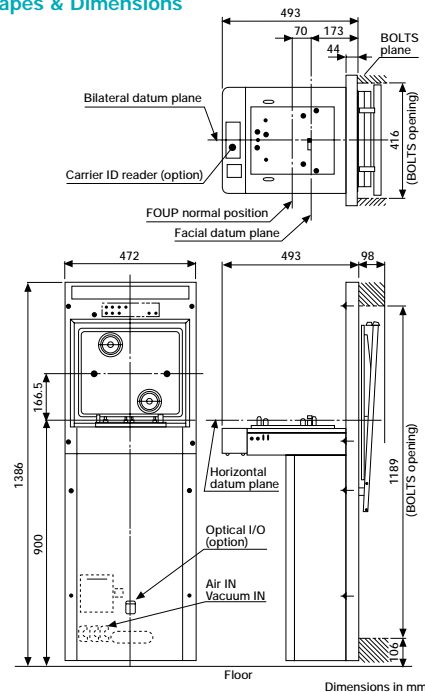
FOUP Load Port: TAS300 300mm Wafer Load Port



Key Features

- Compliance: SEMI E15.1, E57, E62, E63, E64, S2 and S8
- Simple, Robust (MTBF < 150,000 hrs), Cost Effective pneumatic operation
- Particle Free: 0.0003 PWP or less
- High reliability with TDK patented stopper design for all type of FOUPs
- Port door has excellent durability for repetitive operations
- No need to adjust Loadport for each FOUP Vendor
- Options
 - Mapping Unit with Double Wafer Detection
 - CID Kit
 - CE

Shapes & Dimensions



Specifications

Designed for FOUP	300mm FOUP (for 25 wafers) Complies with SEMI E47.1, E62
FOUP clamp	Kinematic pin positioning Employs front retaining feature (air driven)
FOUP door securing	Vacuum suction
Detection Function	Detects presence of FOUP Detects FOUP normal placement position Obstacle detection Detects wafer protrusion within FOUP
Stroke	y-axis (FOUP forward and back motion): 70mm (SEMI standard) z-axis (FOUP door rise and lower motion): 375mm
Repeat accuracy	y-axis (FOUP forward and back motion): ± 0.1 mm z-axis (FOUP door rise and lower motion): ± 0.1 mm
Operation time	Without mapping FOUP open operation: 10s FOUP close operation: 10s With mapping (optional specifications) FOUP open operation: 20s FOUP close operation: 10s
Unit mass	Approx. 55kg
Utility	Power: DC.24V $\pm 5\%$, 3A (full-load current: 2A) Short-circuit breaking capacity: 20A Dry air: 0.52 to 0.6MPa, 5l/min ($\phi 6$ mm air tube) Vacuum: 30 to 50kPa, 10l/min ($\phi 8$ mm air tube)
Options	<ol style="list-style-type: none"> 1. Aluminum frame caster 2. Mapping unit 3. CID <ol style="list-style-type: none"> (1) Keyence BCR (2) Omron RF-IDR/W (3) Hermos Asyst RF-JDR/W 4. Optical I/O 5. Seal (Nichias soft seal T/#9096-TB-54) 6. Ejection detection sensor designed for quartz glass 7. Info Pad <ol style="list-style-type: none"> (1) Info Pad A and B (electrical detection) (2) Info Pad C and B (lock-out pin) 8. Over-rotation latch key 9. Registration pin